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US PTO
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01/14/02

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Priority Application Serial No. 09/026,042
Priority Filing Date February 19, 1998
Inventor Sujit Sharan et al.
Assignee Micron Technology, Inc. and Applied Materials, Inc.
Priority Group Art Unit 1763
Priority Examiner P. Hassanzadeh Ph.D.
Attorney's Docket No. MI22-1902
Title: RF Powered Plasma Enhanced Chemical Vapor Deposition Reactor and Methods
of Effecting Plasma Enhanced Chemical Vapor Deposition

INFORMATION DISCLOSURE STATEMENT

References - - See attached Form PTO-1449

In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to the United States patents and other references listed on the attached Form PTO-1449. No admission is made regarding whether all the submitted references are prior art.

The listed references were cited by, or submitted to, the Office in the parent, co-pending application of the above-identified application. The above-identified application is a divisional application of co-pending application Serial No. 09/026,042, filed February 19, 1998, upon which the above-identified application relies for a priority date under 35 U.S.C. §120. Such prior disclosure is sufficient for the above-identified application as far as copies of the references are concerned. 37 C.F.R. §1.98(d) and MPEP §609(2). As a courtesy, Applicant submits copies of the cited foreign references and articles for review.

Citation of these references is respectfully requested.

Respectfully submitted,



Frederick M. Fliegel, Ph.D.
Reg. No. 36,138

Date: 3/24/2002

Form PTO-1449 LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)					U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-1902	SERIAL NO. Filed Concurrently Herewith	
					APPLICANT Sujit Sharan et al.		FILING DATE		GROUP
					U.S. PATENT DOCUMENTS				
*Examiner Initial		Document Number	Date	Name		Class	Subclass	Filing Date If Appropriate	
	AA	5,942,075	08/24/99	Nagahata et al.					
	AB	5,919,332	07/06/99	Koshiishi et al.					
	AC	5,900,103	05/04/99	Tomoyasu et al.					
	AD	5,865,937	02/02/99	Shan et al.					
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	AF	5,716,534	02/10/98	Tsuchiya et al.					
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	AJ	5,605,637	02/25/97	Shan et al.					
	AK	5,567,267	10/22/96	Kazama et al.					
FOREIGN PATENT DOCUMENTS									
		Document Number	Date	Country		Class	Subclass	Translation	
								Yes	No
	AL	WO 98/32154	1998	PCT					
	AM	EPO 831 679 A1	1998	EPO					
	AN	EPO 776 991 A1	1997	EPO					
	AO	EPO 742 577 A2	1996	EPO					
	AP	0 686 708 A1	1995	EPO					
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)									
	AR		Radio Frequency Matching for Helicon Plasma Sources . J.P. Rayner et al., J. Vac. Sci. Technol. A 14(4) Jul/Aug. 1996, pages 2048-2055.						
	AS								
	AT								
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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				APPLICANT Sujit Sharun et al.				
				FILING DATE		GROUP		
U.S. PATENT DOCUMENTS								
*Examiner Initial		Document Number	Date	Name		Class	Subclass	Filing Date If Appropriate
	AA	5,468,296	11/21/95	Patrick et al.				
	AB	5,439,524	08/08/95	Cain et al.				
	AC	5,433,786	07/18/95	Hu et al.				
	AD	5,272,417	12/21/93	Ohmi				
	AE	5,261,962	11/16/93	Hamamoto et al.				
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	AI	5,102,523	04/07/92	Beisswenger et al.				
	AJ	5,052,339	10/01/91	Vakerlis et al.				
	AK	5,039,388	08/13/91	Miyashita et al.				
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		Document Number	Date	Country		Class	Subclass	Translation
								Yes
	AL	WO 95/32315	1995	PCT				No
12/08	AM	0 678 903 A1	1995	EPO				
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	AO	0 552 491 A1	1993	EPO				
	AP	2 663 806	1991	France				
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)								
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Sujit Sharan et al.

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*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	4,585,516	04/29/86	Corn et al.			
	AB	5,853,484	12/29/98	Jeong			
	AC	6,159,867	12/12/00	Sharan et al.			
	AD						
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		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AL	5-175163	1991	Japan				
	AM	WO 89/02695	1989	PCT				
	AN	08-031806	2000	Japan				
	AO							
	AP							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

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